

**INFORMATION DISCLOSURE STATEMENT**

Applicant : Leskela et al.
App. No. : 09/787,062
Filed : June 28, 2001
For : METHOD FOR GROWING OXIDE THIN
FILMS CONTAINING BARIUM AND
STRONTIUM
Examiner : Matthew A. Anderson
Group Art Unit : 1765

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 3 references that are also enclosed.

Please place these references in the file of the above-identified patent application in accordance with 37 C.F.R. § 1.97(i).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: April 2, 2004

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FORM PTO-449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. SEPP9.001APC	APPLICATION NO. 09/787,062
	APPLICANT Leskela et al.	
	FILING DATE June 28, 2001	GROUP 1765

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
	1. Vehkamäki et al., <u>Growth of SrTiO₃ and BaTiO₃ Thin Films by Atomic Layer Deposition</u> , Electrochemical and Solid-State Letters, 2 (10) pp. 504-506 (1999)
	2. Nakano et al., <u>Digital chemical vapor deposition of SiO₂</u> , Appl. Phys. Lett 57 (11), September 10, 1990, pp. 1096-1098
	3. S.M. Bedair, <u>Atomic layer epitaxy deposition processes</u> , J. Vac. Sci Technol. B 12(1), Jan/Feb 1994, pp. 179-185

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EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	